

Fe-Pt-BN-BASED SPUTTERING TARGET AND PRODUCTION METHOD THEREFOR

ABSTRACT

A problem of particle generation in an Fe-Pt-BN-based sputtering target having a high relative density is resolved by an approach different from conventional methods.

An Fe-Pt-BN-based sputtering target having a relative density of 90% or more and a Vickers hardness of 150 or less can reduce the number of particles generated during magnetron sputtering.